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Substitute for form 1449A/PTO <b>INFORMATION DISCLOSURE      STATEMENT BY APPLICANT</b> <small>(Use as many sheets as necessary)</small>		Complete if Known <b>Application Number</b> 09/945397 <b>Filing Date</b> August 30, 2001 <b>First Named Inventor</b> Sandhu, Gurtej <b>Group Art Unit</b> 2822 <b>Examiner Name</b> Unknown	
<small>Sheet 1 of 16</small> <small>TRADEMARK OFFICE</small> <small>FEB 03 2003</small> <small>SC109</small>		Attorney Docket No: 303.541US2	

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EXAMINER

Michael Trinh

DATE CONSIDERED

4/14/03